Dative bonding as a mechanism for enhanced catalysis on the surface of MoS₂

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Abstract

Transition-metal dichalcogenide (TMD) layers have been a subject of widespread interest as platforms for electronic devices. However, the low chemical activity of their basal plane results in several technological bottlenecks, including high contact resistance at TMD–electrode interfaces, difficult growth of high-quality gate-oxide layers, and challenging functionalization. The simplest, and perhaps only, approach to overcoming those limitations may be to exploit dative bonding. The effect can enhance binding on TMDs, since their chalcogen nonbonding lone-pair orbitals can function as electron donors. Therefore, it should also be able to impact the surface catalysis for reactions that produce acceptors. This computational study seeks to investigate whether $S \rightarrow P$ dative bonding may be an effective mechanism for catalysis on the surface of MoS₂, and whether the sheet can be functionalized via chemical reactions enabled by the binding of PH_n and PCl_n. The results show that the bonding facilitates the PH functionalization of MoS₂. The interaction is strong (1.11 eV), making the whole process exothermic, and the activation energy notably reduced (from 2.08 to 0.5 eV). Furthermore, the mechanism is intrinsically selective, which could prove a vital feature for future advancements in TMD-based electronics, since it could steer selected processes toward surface functionalization or thin-film growth.

Keywords: molybdenum disulfide, transition metal dichalcogenides, catalysis, functionalization, surface interactions

1. Introduction

Two-dimensional (2D) transition metal dichalcogenide (TMD) layers are among the most widely studied materials for potential applications in electronic devices [1-8]. The interest stems from the intrinsic properties of TMDs, which arise due to their characteristic structure. Each TMD sheet comprises one transition-metal layer (Mo, W, Pt, etc.) sandwiched between two chalcogen layers (S, Se, Te). The elements within these three layers bond covalently, adopting either trigonal prismatic (1H, 2H for multilayer) or octahedral symmetry (1T), leaving no coordinatively unsaturated surface sites. Consequently, the basal planes of TMD are often chemically inactive, with external interactions limited to van der Waals (vdW) forces. For most TMDs, the sheets can be either semiconducting (1H) or metallic (1T) [9], and for the former, the size of the bandgap depends on the comprising elements and the number of sheets stacked [10-12]. As a result, TMDs offer good chemical stability and a versatile set of electronic properties, which have benefited several high-performance electronic devices, notably chemical sensors and field-effect transistors (FETs). Detectors based on MoS₂ and MoTe₂ have been reported as highly sensitive to NO₂ even when operating at room temperature [13-17], despite conventional metaloxide-semiconductor (MOS) sensors requiring heating to several hundred °C to operate efficiently [18-20]. Likewise, TMD-based FETs have shown improved performance [21-23] and low device-to-device variation [24], illustrating the maturity of the processing technology.

Still, despite the advantages, the intrinsic properties of TMDs have also resulted in several technological bottlenecks. The low chemical activity of the basal plane often results in a high contact resistance at TMD–metal (electrode) interfaces, which can lower the performance of TMD-based electronic devices [25–27]. Furthermore, the lack of unsaturated surface sites hinders the growth of metal oxides on TMD surfaces, despite many applications requiring high-quality gate oxide layers [28–31]. Limited surface interactions also reduce the number

Given the low reactivity of TMDs, one solution could be to employ reagents that, upon adsorption on the surface of a pristine sheet, would facilitate coordinate covalent (dative) bonding. In most cases, this would imply the use of group III Lewis acids, especially since AlX₃ (X = H, Cl, Br, and CH₃) were predicted to form dative bonds with MoS₂ while in their monomer form [66]. Nevertheless, the compounds are known to dimerize via 3-center 2-electron bonds, and the interaction could prove competitive with the dative bonding due to the conservative binding energy of the latter. Thus, the dimerization could hamper the enhanced adsorption. Furthermore, even if dative bonds form, they were shown to have a limited impact on the molecules. However, with-

of analytes that TMDs can efficiently detect, restricting the application perspectives [32-34]. As a result, significant effort has been put into overcoming those limitations, notably employing substitutional doping [35-39]. The latter has been reported effective in enhancing the local chemical activity of TMDs [40, 41], which has improved the sensitivity of the sheets [42-45] and even facilitated the formation of strong chemical bonds at their surface [46-48]. The doping can be achieved in large-sized single-crystal sheets grown using chemical vapor deposition (CVD) [49-51] and made in pristine sheets employing electron-beam-mediated substitution [52, 53]. Both methods have yielded precise doping levels. However, due to the stochastic nature of the processes, the resulting dopant distribution becomes relatively non-uniform. Hence, despite the reported enhancements, this approach will not be suitable for all applications, especially if a homogeneous functionalization is required. An alternative could be to employ atomic layer deposition (ALD). The technique is well suited to grow highquality continuous films and has already found extensive use in the fabrication of electronic devices [54-58]. However, the main drawback of ALD use with TMDs is that it often requires coordinatively unsaturated surface sites to initiate the growth process. As a consequence, typical ALD setups have shown only limited success, while optimization approaches employ ultraviolet/O3 pre-treatment [59, 60], plasma-enhanced ALD [61, 62], or high-temperature annealing [63, 64] to improve nucleation and film quality. Still, regardless of the method, thin and uniform layers grown on TMDs remain a challenge [29, 65].

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out sufficient weakening of the molecular bonds, the activation barriers for subsequent reactions may prove a challenge. Hence, novel solutions are still needed. One such approach could be to find reactions able to functionalize TMD surfaces, since those could be tailored to specific adsorption mechanisms. As a consequence, this study seeks to investigate whether dative bonding may be an effective mechanism for catalysis on the surface of 1H MoS₂, and thus whether the sheet can be functionalized via chemical reactions enabled by the bonding of reduced reaction products.

2. Computational Details

All computations were based on DFT using the projector augmented wave (PAW) method, plane waves (PW), and pseudopotentials (PP), as implemented in the QUANTUM ESPRESSO suite [67-69]. The employed PPs have included scalar-relativistic and nonlinear core corrections. Due to the slab geometry, the calculations had a dipole correction added to the bare ionic potential [70], and since some of the adsorbates have an uneven number of electrons, all computations were spin unrestricted. The Perdew-Burke-Ernzerhof (PBE) functional [71, 72] was used to approximate the electron exchange-correlation energy, while van der Waals (vdW) contributions to the total energy were treated using Grimme's D3 method [73, 74]. The PBE+D3 treatment has been used since previous reports have shown it to give dative bond energies and distances comparable with those obtained using M06-2X [66, 75] while providing a good description of the electronic properties of TMDs [44, 48]. The PW cutoff energies for the wave function and the electron density were 55 and 450 Ry, respectively. Brillouin-zone integration was performed with a Monkhorst–Pack grid of $6 \times 6 \times 1$ [76]. Higher cutoff and larger grids have been tested, and they had little impact on the modeled adsorption. Computations used a Gaussian broadening of 0.001 Ry since the adsorption could result in covalent bonding and thus notably affect the electronics. During total energy optimization, the positions of all atoms were relaxed with the convergence criteria of $<10^{-4}$ Ry/au for the force and $<10^{-5}$ Ry for the total energy. The partial charges were estimated using Löwdin population analysis. Energy barriers were calculated with the nudged elastic band (NEB) method. Atomic schematics given in Figures 1-9 were generated by the XcrySDen program [77].

 MoS_2 monolayer was modeled in a 2D periodic slab with a 4 × 4 supercell and ~ 25 Å of vacuum space between periodically-repeated slabs, which follows the methodology used in other studies of molecular adsorption on MoS₂ [46–48, 66, 78, 79]. In the preliminary stages, the 3×3 and 5×5 structures were also tested, and the results have shown that the 4×4 supercell is a good fit for the investigated problem. In the model system, the adsorption occurs on the upper surface of the sheet, with the lower side remaining pristine. The asymmetry introduces a surface-normal dipole moment resulting from the electron transfer between the sheet and adsorbates, which, given the periodic boundary conditions, gives rise to an artificial electric field between neighboring slabs. Hence, to compensate, a dipole correction layer (DCL) was added in the middle of the vacuum region [70]. Consequently, the width of the vacuum space was set to allow for placement of the DCL such that its half would not overlap with the region above MoS₂, where molecules would adsorb and react with each other.

3. Results and Discussion

3.1. Interactions on surface of MoS₂

The atomic structure of MoS_2 makes the valence of the comprised atoms satisfied. Hence, its surface lacks coordinatively unsaturated sites. This makes the formation of new covalent and ionic bonds typically unfavorable since it would change the chemical bonding structure of the sheet. As a consequence, such interactions are usually exclusive to defected [46–48] or strained TMDs [80] due to the bonding already being affected. It leaves the interactions with the pristine surfaces of MoS_2 mostly limited to vdW forces [79] unless the adsorbate is able to facilitate a dative bond [66].

A dative bond is a two-center, two-electron covalent bond in which both electrons derive from the same atom. In such an interaction, the satisfied valence will make MoS₂ the electron donor, i.e., MoS₂ will share one of its lone electron pairs with an adsorbate acting as the acceptor. Hence, the electron transfer from MoS₂ will most likely involve states at its valence band maximum (VBM). Those states lie at Γ -point for multilayer MoS₂ and K-point for the monolayer. The difference between Γ and K for the latter is relatively low (~ 100 meV). Hence, the charge transfer from MoS₂ could, in principle, originate from the VBM at both Γ and K, depending on the charge density distribution and geometrical constraints. To gain further insight into dative bond formation, the charge-density contours of VBM are shown in Figure 1.

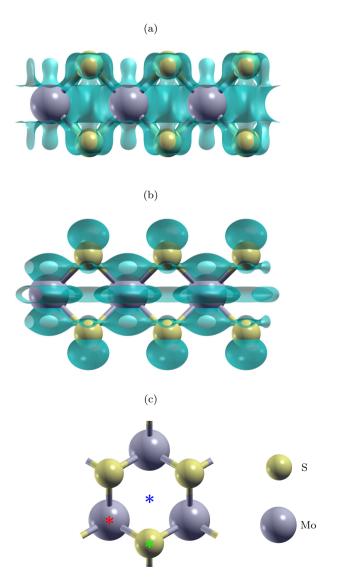


Figure 1: Charge density plots for the VBM of monolayer MoS₂ at (a) Γ -point and (b) K-point of the its (1×1) cell (the isovalue cutoff is 2.5 × 10⁻³ e/au^{-3}). (c) Adsorption sites on the surface of MoS₂: on-top S, on-top Mo, and hollow.

At K, VBM exhibits a low degree of outward projection since most of the charge is distributed within the sheet (see Figure 1a). It reflects the in-plane character of the comprised orbitals, predominantly $4d_{x^2y^2}$ (Mo) and $4d_{xy}$ (Mo). In contrast, VBM at Γ has a high contribution of the $3p_z$ (S) orbitals, which results in notably more outward charge projection (see Figure 1b). This makes the S nonbonding lone-pair orbital the most readily available electron donor on the surface of MoS₂. Thus, Ssite adsorption should be more likely to facilitate dative bonding than other sites like Mo, and hollow (see Figure 1c).

Having the S atoms able to act as an electron donor means that for the dative bond to form, the adsorbate has to be capable of accepting the lone-pair electrons. Such compounds include monomers of Al-bearing Lewis acids (e.g., AlH₃, AlCl₃), which have been reported to adsorb on MoS_2 via $S \rightarrow Al$ dative bond [66]. The mechanism, however, should not be exclusive to group III trichlorides and trihvdrides. Rather, dative bonding should be adopted by compounds in which one of its atoms lacks at least two electrons in its valence shell. Therefore, the surface of MoS₂ could prove a suitable catalyst for reactions that produce such compounds. Those could involve group V trichlorides (trihydrides) and hydrogen (chlorine or fluorine) producing hydrogen chloride (HCl) or hydrogen fluoride (HF) since the byproducts would be electron acceptors. Other processes following the same goal could also prove successful. However, they will be beyond the scope of this investigation, which will focus on phosphorus-bearing compounds. The choice has been motivated by the wide use of phosphine (PH3, see Figure 2a) and phosphorus trichloride (PCl₃, see Figure 2b) in ALD [81-85] and the recent reports showing that phosphorus doping effectively tunes the properties of TMDs [44, 86]. However, other notable advantages of PH₃ and PCl₃ are that they do not dimerize and are easily available.

One of the investigated processes will be a reaction of PH₃ with Cl₂ forming HCl and reduced phosphine. The process will be considered in three stages. At each step, PH_n will dissociate into PH_{n-1} + H, the H atoms will interact with Cl₂ molecules, and HCl will be formed. Each stage will be investigated in gas and on the surface of MoS₂. The

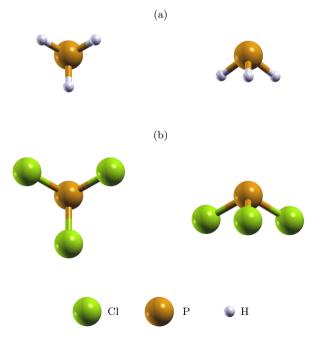


Figure 2: Atomic structures of (a) PH₃ and (b) PCl₃.

former will follow the reactions:

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$$2PH_3 + Cl_2 \xrightarrow{\text{stage 1}} 2PH_2 + 2HCl \tag{1}$$

$$2PH_2 + Cl_2 \xrightarrow{\text{Stage 2}} 2PH + 2HCl$$
 (2)

$$2PH + Cl_2 \xrightarrow{\text{Stage 3}} 2P + 2HCl$$
(3)

which can be summarized as

$$2PH_3 + 3Cl_2 \xrightarrow{\text{Stage 1, 2, 3}} 2P + 6HCl$$
(4)

The latter will follow equivalent reactions, but on MoS_2 , so to differentiate the two, the processes will be denoted as:

C

$$2PH_3@MoS_2 + 3Cl_2 \xrightarrow{Stage 1, 2, 3} 2P@MoS_2 + 6HCl$$
(5)

The second of the investigated processes will be a reaction of PH_3 with F_2 . In this case, three similar stages will also be considered, but rather than forming HCl, they will produce HF, which will make the reaction more energetically favorable than the previous one. Each stage will be investigated in gas and on the surface of MoS_2 , following total formulas:

$$2PH_3 + 3F_2 \xrightarrow{\text{Stage 1, 2, 3}} 2P + 6HF$$
(6)

$$2PH_3@MoS_2 + 3F_2 \xrightarrow{Stage 1, 2, 3} 2P@MoS_2 + 6HF$$
(7)

The third process will involve PCl_3 and H_2 . Similar to the first reaction, this one will also produce HCl, but the byproduct will be reduced phosphorous chloride. The process will be considered in three stages. At each step, PCl_n will dissociate into $PCl_{n-1} + Cl$, and the Cl atoms will interact with H_2 , which will form HCl. Again, each stage will be investigated in gas and on the surface of MoS_2 .

$$2PCl_3 + 3H_2 \xrightarrow{Stage 1, 2, 3} 2P + 6HCl$$
(8)

$$2PCl_3@MoS_2 + 3H_2 \xrightarrow{Stage 1, 2, 3} 2P@MoS_2 + 6HCl$$
(9)

The last process will involve PCl₃ and H₂O. Again, HCl will be formed. However, the P-bearing molecule will not dissociate like in previous cases. Rather, one of the Cl atoms will be substituted by the OH group, i.e., $PCl_n(OH)_m + H_2O \rightarrow PCl_{n-1}(OH)_{m+1} + HCl.$ As a consequence, the reaction will not produce an electron acceptor, which means that the products will not facilitate dative bonding with S atoms of MoS₂. On the other hand, the product will be a less favorable tautomer to phosphorous acid (H₃PO₃), which should be an optimal case for enhanced interactions other than coordinate bonding. Hence, the inclusion of this process serves to illustrate how reactive is the surface in the case where the dative bonding is not the leading mechanism of the surface interactions. The process will be investigated in three stages, and each stage will be considered in gas and on the surface of MoS₂, following two formulas:

$$PCl_3 + 3H_2O \xrightarrow{Stage 1, 2, 3} P(OH)_3 + 3HCl$$
(10)

$$PCl_3@MoS_2 + 3H_2O \xrightarrow{Stage 1, 2, 3} P(OH)_3@MoS_2 + 3HCl$$
(11)

3.2. Adsorption of PH_3 and PCl_3 on surface of MoS_2

Prior to the chemical reactions described in Section 3.1, the adsorption of PH₃ and PCl₃ will be most likely governed by a combination of vdW and electrostatic effects. Thus, the adsorption will not favor one well-defined site but will result in several different configurations characterized by similar adsorption energies and separated by low energy barriers. As a consequence, MoS₂ will not impose a predefined geometry for the reagents to interact. Hence, several distinct configurations should be considered and used for different reaction geometries. Both molecules are a trigonal pyramid (see Figures 2a and 2b), which makes their adsorption describable with two parameters, namely, (i) the position of the side atoms, and (ii) whether the phosphorus is facing towards or away from the surface. In principle, the former could be random. However, due to the hexagonal symmetry of MoS₂, the problem can be reduced to just two rotary configurations. Together this gives four distinct configurations for each molecule to probe the S-site adsorption, i.e., D1 (Figure 3a), D2 (Figure 3b), U1 (Figure 3c), and U2 (Figure 3d). In addition, D1 adsorption will be investigated for Mo and hollow sites (Figures 3e and 3f). The sites are unlikely to facilitate a dative bond. Hence, their inclusion should illustrate the impact of the dative bond on the total energy, and/or if the molecules can spontaneously shift towards more favorable sites during the reactions.

Table 1 summarizes the adsorption of PH₃ and PCl₃ on MoS₂. The parameters include the molecule bond distances ($d_{\text{H-P}}$ and $d_{\text{Cl-P}}$), the vertical separation between the molecule and the surface (h_{mol}), and the adsorption energy (E_{ads}). The latter is defined as

$$E_{ads} = E(PX_3@MoS_2) - E(PX_3) - E(MoS_2),$$
(12)

where $E(PX_3 @MoS_2)$, $E(PX_3)$, and $E(MoS_2)$ are the total energy of the adsorbate-substrate system, free molecule (PH₃ or PCl₃), and the monolayer, respectively. Thus, E_{ads} is positive for endothermic and negative for exothermic processes. The optimized structures of the most and least favorable configurations are shown in Figure 4, while the remaining geometries are included in Supporting Information (see Figures S1 and S2).

The results show that the adsorption of PH₃ and PCl₃ shares qualitative similarities for both molecules. In all investigated cases, the adsorption is an exothermic process. The values of E_{ads} are relatively low, indicating weak surface interactions. This coincides with the large vertical separation between the molecules and MoS₂, which far exceeds the sum of the covalent radii of the interfacing atoms. Furthermore, the molecules themselves show virtually no change upon adsorption or

Table 1: Adsorption of PH₃ and PCl₃ on monolayer MoS₂

Mol.	Site	Config.	Fig.	$-E_{ads}{}^a$	$d_{\mathrm{H/Cl-P}}^{b}$	$h_{ m mol}{}^c$
PH ₃	S	D1	4b	115	1.431	3.809
		D2	S1e	115	1.430	3.811
		U1	4a	174	1.431	3.014
		U2	S1f	172	1.431	3.025
	Mo	D1	S1b	169	1.431	3.237
	hollow	D1	S1a	156	1.431	3.340
PCl ₃	S	D1	4d	236	2.076	3.501
		D2	S2e	237	2.075	3.496
		U1	S2d	360	2.075	3.307
		U2	S2f	356	2.075	3.294
	Mo	D1	4c	375	2.079	2.798
	hollow	D1	S2a	325	2.075	3.019

 ${}^{a}E_{ads}$ is the adsortion energy (eq X, given in meV), ${}^{b}d_{H-P}$ and d_{Cl-P} are the bond distances in the molecules of PH₃ and PCl₃, respectively (given in Å), ${}^{c}h_{mol}$ is the vertical separation between the molecule and MoS₂ (given in Å).

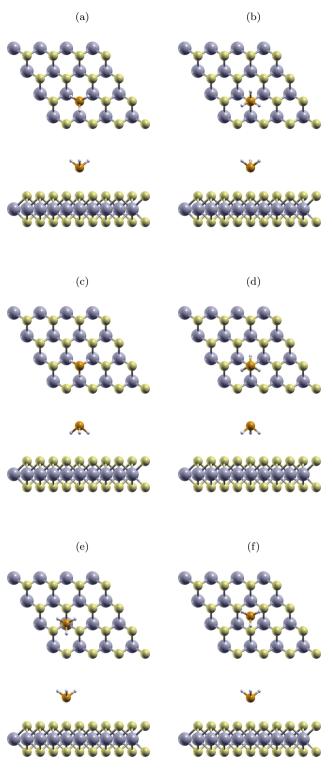


Figure 3: Schematics of initial adsorption geometries (a) D1, (b) D2, (c) U1, and (d) U2 at the S-site. D1 configurations at (e) Mo- and (f) hollow-sites. In the case of PCl₃, the configurations are equivalent.

differences between configurations. Those features are characteristic of the adsorption, where interactions are limited to a combination of vdW and electrostatic effects. Due to their dispersive nature, the positions of the side atoms have a negligible effect on the value of E_{ads} . On the

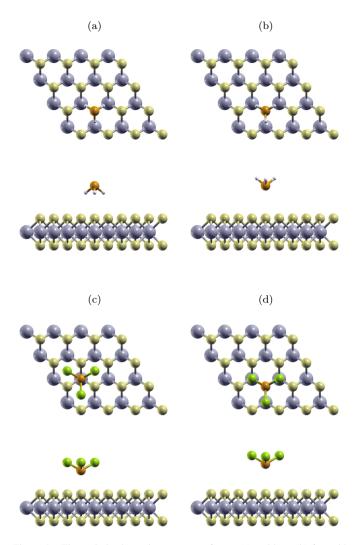


Figure 4: The optimized atomic structures of most (a) and least (b) favorable configuration of PH₃@MoS₂. The optimized atomic structures of most (c) and least (d) favorable configuration of PCl₃@MoS₂.

other hand, adsorption sites and the position of phosphorus show some impact on the adsorption energy. However, at room temperature, these differences should not have a significant effect on the adsorption.

It is also prudent to note that the results show that, regardless of the adsorption geometry, PCl₃ has higher absorption energy than PH₃. The minimum and maximum values of E_{ads} for PCl₃ are -236 and -375 meV, while E_{ads} for PH₃ ranges between -115 and -173 meV. The difference is notable. However, it has nothing to do with the dative bonding. The effect is to be expected, since PCl₃ has a greater dipole moment (0.97 D) than PH₃ (0.58 D). The PCl₃-to-PH₃ ratio of the average E_{ads} (2.19) is comparable to the ratio of the dipole moments of the molecules (2.02), which suggests that vdW forces are the dominant component of the interaction.

3.3. Reactions of PH_3 and PCl_3

Phosphorus has a valence of 3 in both PH₃ and PCl₃. This satisfies the electronic pairs on its valence shell, which means that the molecules will act as electron donors rather than acceptors. Hence, to make them acceptors, a reaction has to reduce the valence. However, this requires the molecules to dissociate, $PX_n \rightarrow PX_{n-1} + X$, which on its own is endothermic, but, at least in principle, could be offset by the exothermic formation energy of the other reaction products and the formation of $S \rightarrow P$ dative bond, making the reaction favorable. Furthermore, since each dissociation will impact the molecular bonds, some stages may prove more favorable than others, and thus each should be investigated to elucidate the total energy of the reaction (E_{rxn}) and the molecule-sheet interactions (i.e., E_{ads}). The latter will be best illustrated by the difference between the reaction energies occurring on MoS₂ and in gas

$$E_{\rm ads} = E_{\rm rxn} (@MoS_2) - E_{\rm rxn} (gas), \tag{13}$$

where each E_{rxn} will differ for each reaction. In the case of the Cl₂ + PH₃, the reaction energy in gas will follow the formula

$$E_{\rm rxn} = E(\rm PH_{3-n}) + nE(\rm HCl) - E(\rm PH_3) - \frac{n}{2}E(\rm Cl_2), \qquad (14)$$

where *E* is the total energy, and *n* is the stage of the reaction (n = 0, 1, 2, 3). Consequently, E_{rxn} of $Cl_2 + PH_3$ reacting on MoS₂ will be calculated as

$$E_{\rm rxn} = E(\rm PH_{3-n}@MoS_2) + nE(\rm HCl) - E(\rm PH_3) - E(@MoS_2) - \frac{n}{2}E(\rm Cl_2).$$
(15)

Therefore, E_{rxn} represents the total energy of the products relative to the energy of non-interacting reagents. By analogy, the reaction energy for F₂ + PH₃ occurring in gas and on MoS₂ will follow formulas

$$E_{\rm rxn} = E(\rm PH_{3-n}) + nE(\rm HF) - E(\rm PH_3) - \frac{n}{2}E(\rm F_2), \qquad (16)$$

$$E_{\rm rxn} = E(\rm PH_{3-n}@MoS_2) + nE(\rm HF) - E(\rm PH_3) - E(@MoS_2) - \frac{n}{2}E(\rm F_2).$$
(17)

Finally, the values of E_{rxn} for the last dissociative reaction $H_2 + PCl_3$ will be calculated using formulas

$$E_{\rm rxn} = E(\rm{PCl}_{3-n}) + nE(\rm{HCl}) - E(\rm{PCl}_3) - \frac{n}{2}E(\rm{H}_2), \qquad (18)$$

$$E_{\rm rxn} = E({\rm PCl}_{3-n} @MoS_2) + nE({\rm HCl}) - E({\rm PCl}_3) - E(@MoS_2) - \frac{n}{2}E({\rm H}_2).$$
(19)

 $E(PX_{3-n})$ and $E(PX_{3-n}@MOS_2)$ are calculated in such a way that, for each step of the reaction, one X atom of the P-bearing molecule is removed from the system, and then the structure is optimized to give a new total energy. Subsequently, the new geometry becomes the starting point for the next step, and the process continues up to n = 3 (i.e., the bare phosphorus).

Figure 5a shows the values of E_{rxn} for Cl₂ + PH₃ (stage "0" indicates the pre-reaction state of the system). In the gas phase, steps 1–3 have E_{rxn} of 0.48, 0.75, and 2.56 eV, respectively. The trend is not linear, indicating that PH_{3-n} species reconfigure their molecular bonds, which affects the subsequent dissociation energies. The positive values of the reaction energy show that the process is endothermic, meaning that the exothermic formation of HCl is not enough to offset the dissociation, and thus for this reaction to be favorable, the difference would have to be compensated by enhanced molecule-sheet interactions of the byproducts.

In the case of $Cl_2 + PH_3 @MoS_2$, there is no one geometry for the reagents to interact. Hence, the three-step procedure has been repeated for all adsorption configurations discussed in Section 3.2. Still, despite the differences in the initial position of PH₃, all computations have converged on the qualitatively same geometries and thus are equivalent for stages 1–3. For stage 0, Figure 5a shows E_{rxn} of the highest- (empty circle, dashed line) and the lowest-energy configurations (full circle, solid

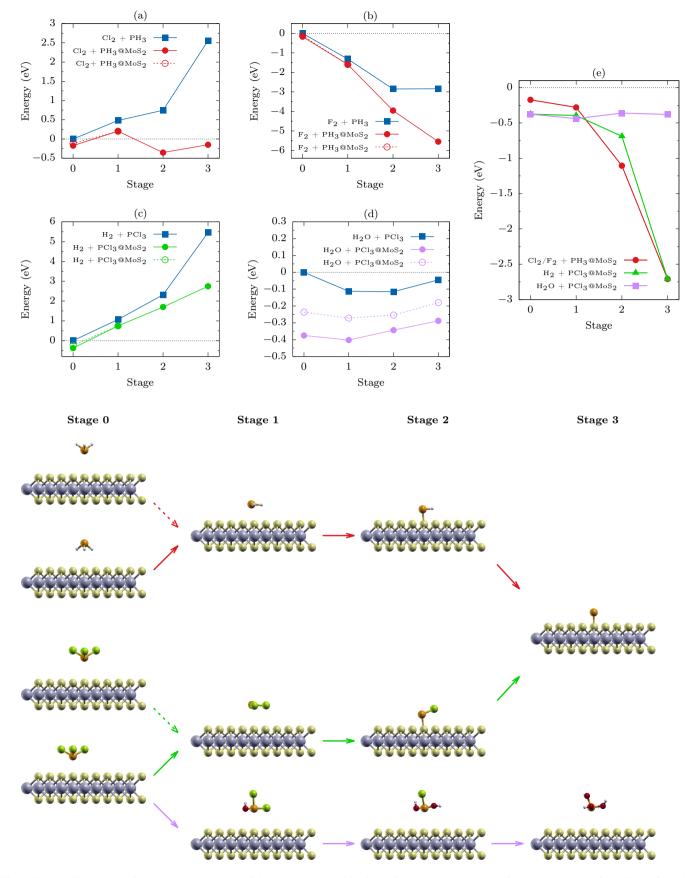


Figure 5: (a-d) The energies of the reactions at each step of the process. For the @MoS₂ configurations only the values for the most and least favorable configurations are shown. (e) The adsorption energies of the phosphorus-bearing products. Bottom half of the figure includes the diagram illustrating the structures at each stage of the reaction, arrow types coincide with the line styles used in the graphs a-e.

line). Both structures are also included in the diagram in Figure 5, where the dashed arrow leads from the highest-energy configuration, while the solid one leads from the lowest. In stage 1, the loss of the H atom causes PH2 to favor a geometry where the molecule orients itself "flat" centered at the nearest-neighbor S-site (see stage 1 graphic in Figure 5). The molecule binds more strongly to the surface. However, the effect is limited ($E_{ads} > -0.17$ eV for PH₃ vs. $E_{ads} \approx -0.28$ eV for PH₂, see Figure 5e) and thus cannot be a result of dative bonding. More likely, this is a product of a weak bonding interaction between the unpaired electron of phosphorus and the lone pair of sulfur, since it would account for the small increase of E_{ads} and the reduced, but still relatively large, distances between the atoms (> 3.5 Å for PH₃ vs. ≈ 2.8 Å for PH₂). As a consequence, the change in binding energy is insufficient to compensate for the dissociation or compete with the adsorption. Thus, the first stage on MoS₂ is slightly endothermic $(E_{\rm rxn} = 0.2 \text{ eV})$ but more favorable than reacting in the gas phase. In stage 2, PH₂ dissociates into PH and H, which has a notable impact on the molecule-sheet interactions. PH retains the in-plain configuration, but the phosphorous shifts towards the nearest sulfur atom (see stage 2 in Figure 5). The resulting S–P distance is only 2.069 Å, which is within the sum of the covalent radii of both atoms. This coincides with a charge transfer from $3p_z(S)$ orbital to 3p(P) and a significant increase of adsorption energy ($E_{ads} = -1.11$ eV, see Figure 5e). In contrast, the sheet of MoS₂ remains unaffected. Hence, the only mechanism that could account for the effect is an $S \rightarrow P$ dative bonding. The interaction becomes favorable since the phosphorus in PH lacks two electrons to satisfy its valence, making the molecule an electron acceptor and thus allowing a donation of lone-pair electrons. The strong binding reduces the reaction energy to -0.35 eV, making stage 2 exothermic and favorable over simple adsorption of PH3. This illustrates that dative bonding on the surface of MoS₂ can enable the catalysis of a reaction, which otherwise is endothermic. Finally, in stage 3 the last H-P bond breaks, leaving a bare phosphorus. It increases the adsorption energy of P even further ($E_{ads} = -2.71$ eV, see Figure 5e). However, since the last dissociation is the most endothermic, the resulting E_{rxn} is only -0.15 eV (see Figure 5a). As a consequence, the third remains exothermic, but it is less favorable than the second stage. Hence, the PH functionalization of MoS₂ remains the lowest energy configuration of the system.

Figure 5b shows the values of E_{rxn} for F_2 +PH₃ and F_2 +PH₃@MoS₂. In contrast to the previous reaction, $F_2 + PH_3$ is predicted energetically favorable, with stages 1–3 having E_{rxn} of –1.32, –2.85, and –2.84 eV, respectively. The results indicate that a dative bond is not required to enable the dissociation of PH₃, and that the reaction should be able to initiate without MoS₂. However, this should not be confused with the surface having a negligible impact on the process. The low reaction energy of F₂ + PH₃ stems from the exothermic formation of HF. It offsets the endothermic dissociation of F2 and PH3 in stage 1, continues in stage 2 with the dissociation of F_2 and PH_2 , but ends at stage 3, where formation energy of HF is only able to equal the exothermic dissociation of F_2 and PH (stages 2 and 3 have virtually identical E_{rxn} , see Figure 5b). This means that HF formation is not a sufficient mechanism to facilitate stage 3. Thus, other exothermic effects are required. The results show that one of those could be dative bonding on MoS₂. Figure 5b illustrates that each stage of $F_2 + PH_3@MoS_2$ has a lower value of E_{rxn} than $F_2 + PH_3$. The difference for subsequent steps becomes more pronounced due to the enhanced adsorption of the P-bearing compounds (see Figure 5e). This makes each step of $F_2 + PH_3 @MoS_2$ more favorable than the previous. Therefore, improving the catalysis for processes on MoS₂.

Figure 5c gives E_{rxn} for H₂+PCl₃ and H₂+PCl₃@MoS₂. In contrast to both previous processes, the reaction is not energetically favorable. In gas, the reaction energies for stages 1–3 are 1.07, 2.32, and 5.46 eV,

respectively. The values indicate that the formation of HCl is insufficient to offset the dissociation of H₂ and PCl₃. On MoS₂, the difference is reduced by the molecule-sheet interactions, but the reaction energy remains positive. In stage 1, the loss of the Cl atom causes all initial configurations to favor a geometry where PCl₂ orients itself in-plane, centered at the nearest-neighbor S-site, as was the case for PH₂ (see stage 1 graphic in Figure 5). The dissociation has a limited impact on the adsorption energy ($E_{ads} = -0.4$ eV, see Figure 5e). However, this changes in stage 2. Here, PCl aligns itself flat with the phosphorous above the nearest sulfur atom (see stage 2 in Figure 5). It results in an S–P distance of 2.114 Å and an E_{ads} of –0.69 eV. The S \rightarrow P bond energy for PCl@MoS₂ is comparable to $S \rightarrow Al$ for AlH₃@MoS₂ (-0.7 eV) and AlCl₃@MoS₂ (-0.79 eV) [66]. However, all three are notably weaker than $S \rightarrow P$ for PH@MoS₂ (-1.11 eV), suggesting that less electronic charge available on the molecule demands a stronger dative bonding. Finally, at stage 3, both PH₃@MoS₂ and PCl₃@MoS₂ processes converge on the same structure, giving rise to strong binding of the phosphorous atom ($E_{ads} = -2.71 \text{ eV}$). Still, the effect is not enough to compensate for the dissociation of PCl₃. Hence, all stages remain endothermic, which shows that a process can be unfavorable even if dative bonds can form.

The results discussed so far have covered only reactions that facilitate dative bonding. Hence, it is prudent to contrast the findings with a process where the mechanism is unavailable, i.e., $H_2O + PCl_3$. In this case, the P-bearing molecule will not dissociate, but Cl atoms will be substituted by OH groups, as denoted by formulas (10) and (11). The reaction will not produce electron acceptors, and thus dative bonds will not be formed. The values of $E_{\rm rmx}$ for the substitution will be calculated using formulas

$$E_{\text{rxn}} = E[\text{PCl}_{3-n}(\text{OH})_n] + nE(\text{HCl}) - E(\text{PCl}_3) - nE(\text{H}_2\text{O}), \quad (20)$$

$$E_{\text{rxn}} = E[\text{PCl}_{3-n}(\text{OH})_n @\text{MoS}_2] + nE(\text{HCl}) - E(\text{PCl}_3 @\text{MoS}_2) - nE(\text{H}_2\text{O}),$$
(21)

where *E* is the total energy, and *n* is the stage of the reaction. Figure 5d shows the values of E_{rxn} for H₂O + PCl₃ and H₂O + PCl₃@MoS₂. For the reactions on MoS₂, only the values for the most and least favorable configurations are shown. The atomic structures of the former are also given at the bottom of the diagram in Figure 5. The results show that in gas, the reaction is slightly exothermic, which corresponds with the molecule being a tautomer of H₃PO₃. However, even in their less stable forms, the products do not facilitate improved binding with the surface of MoS₂. The adsorption has no significant effect on the molecular bonds, the molecule-sheet distances are high (> 3.3 Å), and the binding is weak, all indicating that the adsorption is governed by vdW forces. However, due to the dispersive nature of the interactions, the adsorption energy shows little change despite the substitution (see Figure 5e), which means that MoS₂ will not catalyze the reaction.

The investigated processes illustrate that MoS_2 can affect the reaction energy. However, the effect can vary notably. It depends on whether the reaction facilitates the formation of dative bonds, which in turn requires products that are electron acceptors. Without them, surface interactions remain governed by vdW forces. Thus, making the impact of MoS_2 negligible. As a consequence, the effect is not available to all reactions, and thus it cannot be employed universally for enhanced surface catalysis on MoS_2 . Nevertheless, this could also prove an advantage, since the intrinsic selectivity of the mechanism may steer some processes toward surface functionalization and/or thinfilm growth. The effectiveness would depend on the competing paths, but if the functionalization was an exothermic reaction, and the corresponding activation energy would be sufficiently low, dative bonding could make the process dominant.

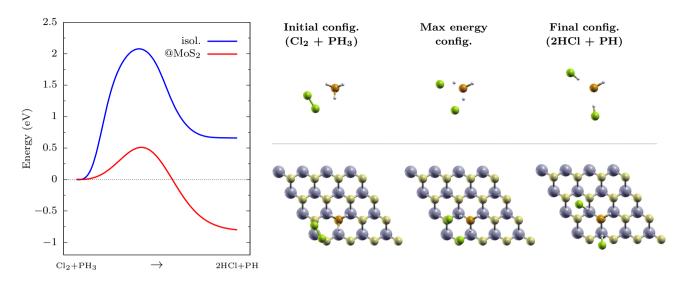


Figure 6: NEB paths calculated for (blue) $Cl_2 + PH_3 \rightarrow 2HCl + PH$ and (red) $Cl_2 + PH_3 @MoS_2 \rightarrow 2HCl + PH@MoS_2$.

Cl₂ + PH₃@MoS₂ is predicted endothermic in stage 1 and exothermic for stages 2 and 3. This suggests that the most likely scenario for the process is going directly from stage 0 to stage 2, i.e., a case where one Cl₂ reacts with one PH₃ forming two HCl and one PH. Figure 6 shows the energy barriers of the reaction in gas and on MoS₂. The former represents an endothermic process. However, it is included for the purpose of comparison. The results show that the surface has a notable effect on both the final energy and the corresponding barrier. In gas, the activation energy is 2.08 eV, while on MoS₂, this is reduced to just 0.5 eV. The difference coincides with the shift in final energy, which indicates the dominant role of the $S \rightarrow P$ dative bond even at the early stages of the process. The role of the molecule-sheet binding is further illustrated by the reaction paths. In both cases, the processes adopt equivalent configurations, and thus the only difference that could significantly affect the barrier height is the $S \rightarrow P$ bond. It is also important to note that the lower values of the final energy relative to the values given in Figure 5a result from HCl adsorption on MoS₂. The latter is not included in the $E_{\rm mx}$ to focus only on the exothermic impact of dative bonding. Together, the results suggest that MoS_2 could have a notable impact on the formation of HCl. However, this still depends on the competing reactions. In this case, the most likely alternative would be a process where Cl substitutes H and H₂ is formed as it would produce a precursor to PCl₅.

Figure 7 shows total energy as a function of reaction coordinates for $Cl_2 + PH_3 \rightarrow H_2 + PHCl_2$ and $Cl_2 + PH_3 @MoS_2 \rightarrow 2HCl + PH@MoS_2$. The results show that both reactions are exothermic but have notably different energies. The formation of Cl - P bonds in PHCl₂ results in a lower reaction energy (-1.61 eV) than the formation of PH on MoS₂ (-0.8 eV). However, the former has a significantly higher barrier of 1.78 eV, resulting from the dissociation of PH₃ and Cl₂ (see the maximum energy configuration in Figure 7). On the other hand, the S \rightarrow P bond enables the low barrier of 0.5 eV for the latter. Hence, due to the low activation energy, the functionalization on MoS₂ should be a faster reaction outside of the high-temperature, high-pressure limit, whereas, within it, the H-to-Cl substitution should become dominant due to the lower total energy.

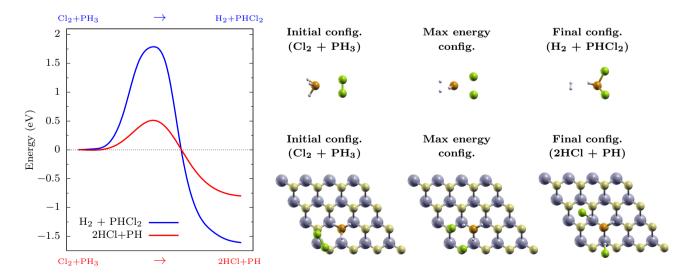


Figure 7: NEB paths calculated for (blue) $Cl_2 + PH_3 \rightarrow H_2 + PHCl_2$ and (red) $Cl_2 + PH_3 @MoS_2 \rightarrow 2HCl + PH@MoS_2$.

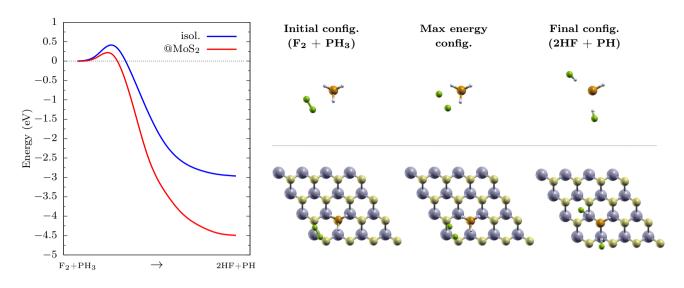


Figure 8: NEB paths calculated for (blue) $F_2 + PH_3 \rightarrow 2HF + PH$ and (red) $F_2 + PH_3 @MoS_2 \rightarrow 2HF + PH @MoS_2$.

In the case of F_2 +PH₃, HF formation will most likely be a dominant reaction, resulting from the strong binding between H and F, and the relatively weak bonds of P and F. Thus, the effectiveness of HF formation will mostly depend on the activation energy. Figure 8 shows total energy as a function of reaction coordinates for F_2 + PH₃ \rightarrow 2HF + PH occurring in the gas phase and on the surface of MoS₂. The results illustrate that MoS₂ has a considerable impact on the final energy but a limited effect on the height of the energy barrier. The low value of the final energy is facilitated by the S \rightarrow P bonding and the physisorption of HF, similar to the effects described for Cl₂ + PH₃. However, unlike the reaction with chlorine, the dative bonding is not formed immediately alongside the dissociation of fluorine. F – F bonds are weaker than the Cl – Cl, and thus at the early stages of the reaction, F₂ breaks first with only some bending of H – P bonds in PH₃ (see the maximum energy structures in Figure 8). This means that there are no available electron acceptors, since PH is not fully formed. Consequently, the impact of MoS_2 on the barrier height is limited, shifting the value by -0.27 eV. Even so, the difference is still relevant because the original value is low (0.41 eV). As a consequence, the barrier on MoS_2 is only 0.16 eV, which means that the reaction could be considerably faster on the surface.

Considering that the results predict a few routes for PH functionalization of MoS_2 , it remains prudent to investigate whether surface diffusion of adsorbed species is possible. The lowest energy path for PH diffusion between two nearest-neighbor S-sites is shown in Figure 9. The NEB computations give the PH path with P moving linearly between the sites and H moving alongside. The path has two maxima (configurations "a" and "c" in Figure 9) and a local minimum right between the S-sites (configuration "b"). The results give the total activation energy of ≈ 0.8 eV. This suggests that the diffusion is possible as the value

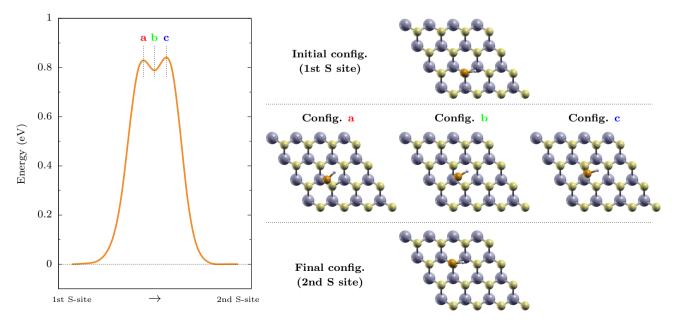


Figure 9: NEB paths calculated for PH diffusion between nearest-neighbor S-sites.

is sufficiently lower that the PH desperation energy of 1.11 eV. However, since the barrier is still high, the process will be slow and limited to high temperatures. Thus, the metastable configuration will have a neglectable impact on the diffusion as it is separated by small energy barriers of only ≈ 20 meV.

4. Conclusions

The present work demonstrates a computational investigation of the functionalization of MoS_2 via chemical reactions that facilitate dative bonds between the products and the MoS_2 substrate. To achieve that the investigation employs the dissociation of phosphine and phosphorus trichloride. The results show that the reduced valence of the phosphorus enables the donation of electrons from $3p_z(S)$ orbitals to 3p(P) in an $S \rightarrow P$ dative bond. The predicted binding is strong and shown to occur for all initial configurations. It enables the interaction to affect the catalysis, but the effectiveness depends on the reaction.

The mechanism seems to be the most successful in combination with moderately endothermic processes like HCl and PH_n formation from Cl₂ and PH₃. In gas, the reaction is predicted endothermic. However, dative bonding makes the process exothermic, favoring the PH functionalization of MoS₂. The interaction also significantly lowers the activation energy (from 2.08 to 0.5 eV), which could make the reaction dominant in the mid-temperature limit, since processes like PCl₅ formation require much higher activation (1.78 eV). Dative bonding can also improve the catalysis for more energetically favorable reactions, e.g., F₂ and PH₃ producing HF and PH_n, acting as another exothermic component. Thus, compensating for the endothermic dissociation and lowering the total energy. However, for highly exothermic processes, e.g., H₂ and PCl₃ forming HCl and PCl_n, S \rightarrow P is insufficient to compensate for the dissociation, and thus the mechanism is unable to facilitate such reaction on the surface of MoS₂.

Finally, the results show a stark contrast to reactions where dative bonding is unavailable, i.e., H_2O and PCl_3 forming HCl and $P(OH)_3$. Here, the interactions with the adsorbates are limited to weak vdW and electrostatic effects, which results in MoS_2 having virtually no effect on the catalysis of the reaction. The results illustrate that dative bonding is crucial for enhancing catalysis on MoS_2 . However, this requires products that are electron acceptors. Thus, the effect is not available to all reactions. Nevertheless, the intrinsic selectivity of the mechanism could prove an advantage, since it can steer selected processes toward surface functionalization and/or thin-film growth. Therefore, the mechanism could prove vital for future advancements in TMD-based electronics.

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